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NIKON CORPORATION 6-3, Nishiohi 1-chome, Shinagawa-ku, Tokyo 140-8601, Japan phone: +81-3-3773-9026 fax: +81-3-3773-9062 http://www.nikon-instruments.jp/eng/

NIKON INSTRUMENTS INC. 1300 Walt Whitman Road, Melville, N.Y. 11747-3064, U.S.A. phone: +1-631-547-8500; +1-800-52-NIKON (within the U.S.A. only) fax: +1-631-547-0306

http://www.nikoninstruments.com/ NIKON INSTRUMENTS EUROPE B.V. Laan van Kronenburg 2, 1183 AS, Amstelveen, The Netherlands phone: +31-20-44-96-222 fax: +31-20-44-96-298

http://www.nikoninstruments.eu/ NIKON INSTRUMENTS (SHANGHAI) CO., LTD. CHINA phone: +86-21-5836-0050 fax: +86-21-5836-0030 (Beijing branch) phone: +86-10-5869-2255 fax: +86-10-5869-2277 (Guangzhou branch) phone: +86-20-3882-0552 fax: +86-20-3882-0580

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NIKON SINGAPORE PTE LTD. SINGAPORE phone: +65-6559-3618 fax: +65-6559-3668 NIKON MALAYSIA SDN. BHD. MALAYSIA phone: +60-3-78763887 fax: +60-3-78763387 NIKON INSTRUMENTS KOREA CO., LTD. KOREA phone: +82-2-2186-8410 fax: +82-2-555-4415





www.nitech.co.kr Tel. 02-6925-1048



Delivers fast, versatile auto-focus with the newly developed and unique Hybrid Auto-Focus system. The LV-DAF makes the most of two types of auto-focus systems.

Comes with Nikon's Auto-Adjustment Program, increasing efficiency by ensuring rapid startup.

Supports a variety of observation methods, including brightfield, darkfield, and differential interference contrast (DIC), as well as various transparent samples such as liquid crystal and glass panels.

Dynamic Auto-Focus Unit for Microscope System Integration LV-DAF





# **Dynamic Auto-Focus Unit for Microscope System Integration**









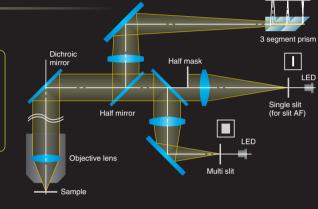
# The Hybrid Auto-Focus features large focus range and fast tracking ability

### What is Hybrid Auto-Focus?

There are two common types of auto-focus systems for microscopes: slit projection and contrast detection.

Slit projection system projects a slit image and then detects the shift in the reflected light. This system is useful when a large focal range is necessary.

Contrast detection system projects a slit pattern and then detects the contrast of the reflected light. This system is useful when focus accuracy is needed. This is possible because this auto-focus system is less affected by sample surface variation.



CCD

Hybrid Auto-Focus combines the advantages of both systems and makes the most of their paired potential.

#### Features

- Tocal range is remarkably larger than with contrast detection alone. This means that samples with distortions on their surface, such as a liquid crystal substrate, can be rapidly tracked, thereby enabling speedy focusing.
- 2 The LV-DAF uses a bright LED for the auto-focus light source. And since it also automatically adjusts the auto-focus light volume for the sample, it can support samples ranging from low to high reflectivity.
- 3 A wide range of observation methods is supported, including brightfield, darkfield, and DIC. Reflective samples and transparent samples are also both supported
- 4 The Auto-Adjustment Program, that is included as standard, enables simple and speedy system setup. The program performs immediate auto-adjustment after the user focuses the system and presses the button to start the setup. It is also possible to automatically set/register optimal parameters for each type of sample and recall them in accordance to the sample being photographed.
- **5** The LV-DAF can be controlled from a PC or a DS-L2 digital camera system for microscopes via USB or RS232C.
- 6 The LV-DAF can be combined with other LV series products. When combined with the LV-ECON, it enables observation under the optimal conditions for each particular sample.
- 7 The controller features the same hardware design as the LV-ECON and has a compact footprint that allows them to be stacked on each other and used anywhere
- B Nikon provides a software development kit (SDK) for integrating the LV-DAF into a variety of systems. (Compatibility is only guaranteed for Nikon products.)

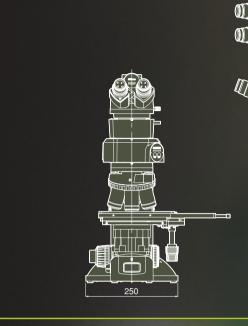
#### **Product** specifications

Detection system	Hybrid system combining slit projection with contrast detection
Auto-focus light source	Near-IR LED (λ = 770 nm)
Objective lens	CFl₀₀ objective lens 2.5x-100x (includes extra-long working distance (ELWD), super-long working distance (SLWD),
	and CR for LCD substrate inspection)*1
Auto-focus modes	Continuous mode and search mode (single, continuous)
Focal range	Focal range without searching (brightfield)*2
	2.5x: 5.5 mm or more, 5x: 4.5 mm or more, 10x: 1.3 mm or more, 20x: 320 $\mu$ m or more, 50x: 50 $\mu$ m or more,
	100x: 10 μm or more
Focal time	0.7 seconds or less (20x: 200μm with no search)*2 *3
Focal precision (repeated reproducibility)	1/2 or less of focal depth*2 *3
AF offset feature	Enables observation with precise adjustment of focal position while applying auto-focus
Minimum drive resolution	0.05 µm*1
External communication	RS232C, USB, and parallel I/O
Power source	100-240 V AC, 1.0 A, 50/60 Hz

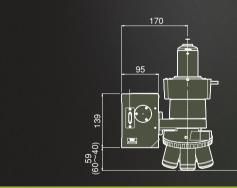
\*1. Some limitations for 2.5x and 100x. \*2. Using Nikon's standard Cr vapor deposition sample. \*3. Using the LV-IMA or LV-FMA. Note: The LV-ECON Controller (available separately) is required when using a motorized revolve







#### LV-DAF + LV-IMA + LV-EPILED (System integration set)



## LV-DAF (unit)

